# The Elektros ETEM 101 Electrostatic TEM

## Designed by Gertrude Rempfer

#### **Electrostatic TEMs**

The possibility of both magnetic and electrostatic electron lenses was first realized by Busch, in 1926. In the 1930s, electron microscopes with magnetic lenses were being developed by Ruska and colleagues at the Technical University and at Siemens, both in Berlin, while Brüche and colleagues developed electron microscopes with electrostatic lenses at the AEG research laboratory, also in Berlin. In the late 1930s to mid-1950s, electrostatic TEMs were also built by GE and Farrand in the US, in Switzerland by Trüb, Täber & Cie., by Zeiss-Jena, and in France by CSF. The maximum accelerating voltage eventually increased to 70 kV and resolution reached nearly 1.5 nm.

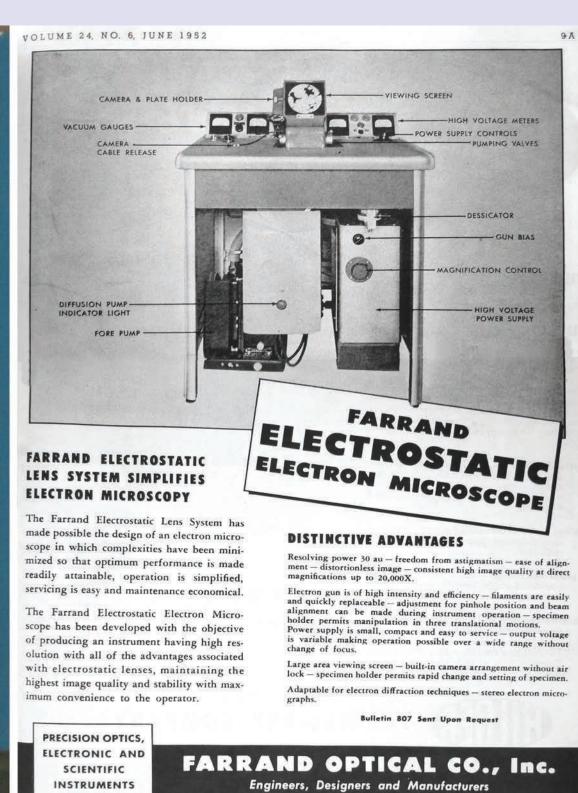
Development of electrostatic TEMs was terminated in the 1950s because magnetic TEMs could have higher resolution (the lenses had shorter focal lengths and lower aberrations), and a higher acceleration voltage (electrostatic lenses operated at nearly the accelerating voltage, thus insulation was a problem). Today, electrostatic columns are found in FIB instruments and in some SEMs (e.g. "micro-SEMs").

#### Rempfer's involvement with earlier electrostatic TEMs

Left: A 1949 AEI/Zeiss EM8 electrostatic TEM. AEG electrostatic TEMs were designed by H. Boersch and H. Mahl. The first model, EM5, was available in 1940, EM6 in 1944, EM7 in 1947, and EM8-I in 1949. In 1949, Zeiss took over production of this type up until 1956, ending with the EM 8-IV. Rempfer tested this 1949 TEM while diverted from Farrand to the Naval Research Laboratory. She found it wanting: "AEG gave electrostatics a bad name". This TEM is now in the collection of the National Museum of the History of Medicine.

Right: A 1952 advertisement for a Farrand electrostatic TEM, based on a Rempfer design. Farrand insisted on some design features (including the inverted column shown here), which Rempfer felt were inadvisable, and she left the Ferrand company. This TEM, constructed after Rempfer left Ferrand, in 1951, was never successfully deployed. While at Farrand, she was not allowed to publish, and most patents (e.g. real-time stereo) were assigned to Rüdenberg. Rüdenberg, a consultant to Farrand, tried to defend his original patent for the EM, which he filed days after Ernst Ruska's first lecture presenting the EM.





BRONX BLVD. & E. 238th ST., NEW YORK 70, N. Y.

#### Comparison between magnetic and electrostatic lenses

Note that the magnetic lines of force are contained within an electrostatic lens, but not within a magnetic lens. Thus, with an electrostsatic lens there is no leakage of fields to other lenses.

- No re-alignment when changing focus or magnification.
- No image rotation.
- High-mag focus is retained at all magnifications. • The specimen is not in a magnetic field.
- Influence from external electrical fields is minimized.

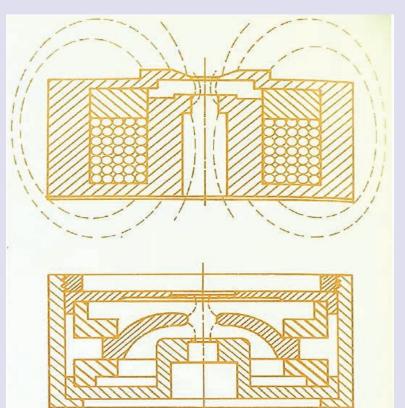


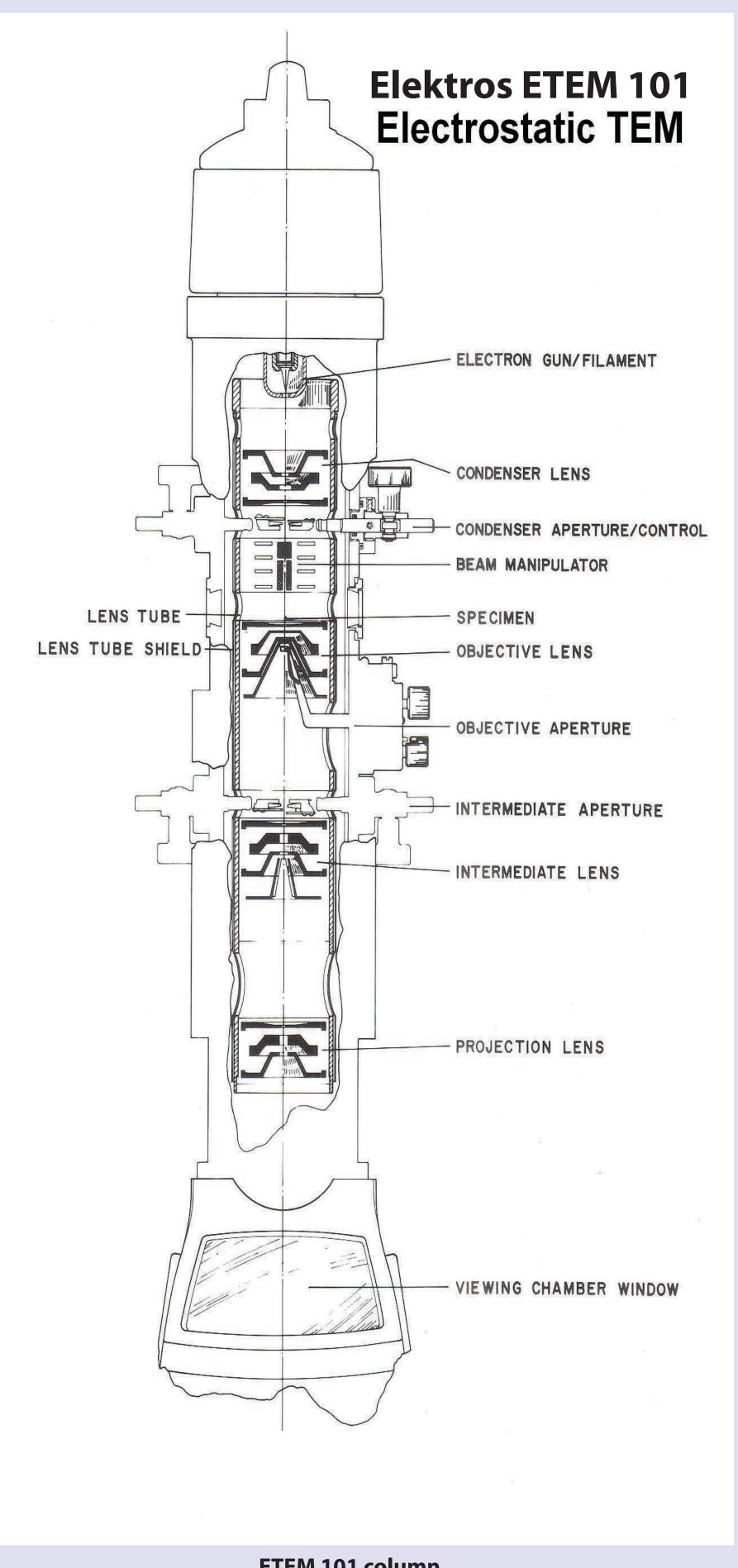
Figure 1 Broken lines show how fields of force escape from magnetic lens pole pieces (top), while electrostatic-lens field is

# **Development of the Elektros ETEM101**

Gertrude Rempfer worked part-time for Tektronix starting in 1963. Working with her former student, Tom Holce, prototype electrostatic TEMs (shown at top left and middle) were built there around 1968. Tektronix was initially interested in commercialization, under the trade name Mlkros. The Tekronics museum has a 1969 version of one of these TEMs, shown at top right).

Rempfer then moved to the Elektros company, a Tektronics spin-off formed in 1970, in Tigard, OR. The company, whose President was Bert Cathery (shown at lower left operating a prototype), included Jon Orloff, who later recounted some of its history, and Arnold Frisch, who complely redesigned the electronics from the Tektronics Mikros prototype. Construction at Elektros and operation by Rempfer (in a Tek/OPB video) are shown here in the bottom row. From 10 to 40 ETEM 101 TEMs (depending on the source of information) were produced before Elektros closed its doors in 1973.





ETEM 101 column

## elektros presents: The ETEM 101 Transmission Electron Microscope and the IES Image Enhancement System

Since it takes up only 9 square feet of floor space complete with IES video monitor, and can be moved on its own casters, the ETEM 101 can be brought to class as a teaching aid, then returned to the lab to continue its tasks as research tool. Its mobility allows several different departments to share the advantages of the microscope, making it even The ETEM 101 is synonymous with versatility. It offers not only the standard operating modes-bright field, dark field and selected area diffraction-bu features exclusive on-screen stereo viewing. Of course, all of these operating modes, including stereo, may be displayed on the IES's TV screen At the heart of the ETEM 101 is a completely automatic vacuum system. The system is activated by ush-button controls to start the vacuum sequence, open the camera, open the column, or turn off the system. Typical operating vacuum is in the 10 5 torr range, and is constantly monitored by means of LED digital readouts and a lighted vacuum schematic on the microscope's front panel.



n electronic fine focus control is provided, calibrated

n 0.2-micron increments for precision through-focal



Its magnification capability enables the user to "zoom " on what appears as very small detail even at top nicroscope magnification, and view it on the TV onitor screen enlarged an additional 22 times. ocusing and astigmatism correction become almost leasurable. And the entire staff or class can watch without needing dark-adaptation Another great advantage of the IES is its versatility in presenting the enhanced image. The video output can be displayed simultaneously on as many as 0 monitors of any size, which greatly increases the system's usefulness as a teaching tool. provides the ability to view images too dim to see n a normal TEM viewing screen. Information can be btained from even the lowest contrast specimen. Because the operator can decrease the level of microscope beam current required for good illumination, a specimen that would be destroyed in one minute of viewing under normal illumination levels can be viewed

A specimen chamber airlock obviates the need to vent the entire column to atmosphere for a specimen change—the microscope is operable within 10 sec onds after specimen insertion The image-recording system of the ETEM 101 is automatic and cleanly functional. It includes automatic exposure meter, electrostatic shutter, and digital on video-tape. The signal can also be processed by counters for micrograph serial number and exposures other kinds of image enhancement systems, either remaining. Each micrograph is automatically imprinted directly or from one of the stored forms. with a serial number and magnification micron marker.

or cut film, and a 70mm, 50-exposure roll-film camera

s available. Each camera is door-mounted for full

access during film change or maintenance; com-

partmented cassettes allow easy access to exposed

plates without advancing the complete series.

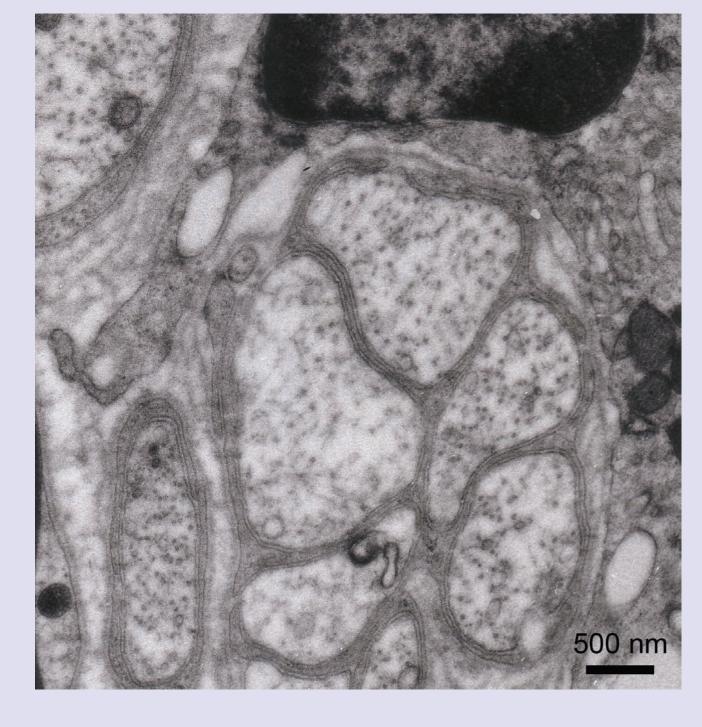
ing computers or stored in scan-converter systems or fective materials and workmanship for one year. warranty is supported by a one-year full service tract. Service is provided by a network of over trained service engineers throughout the country.

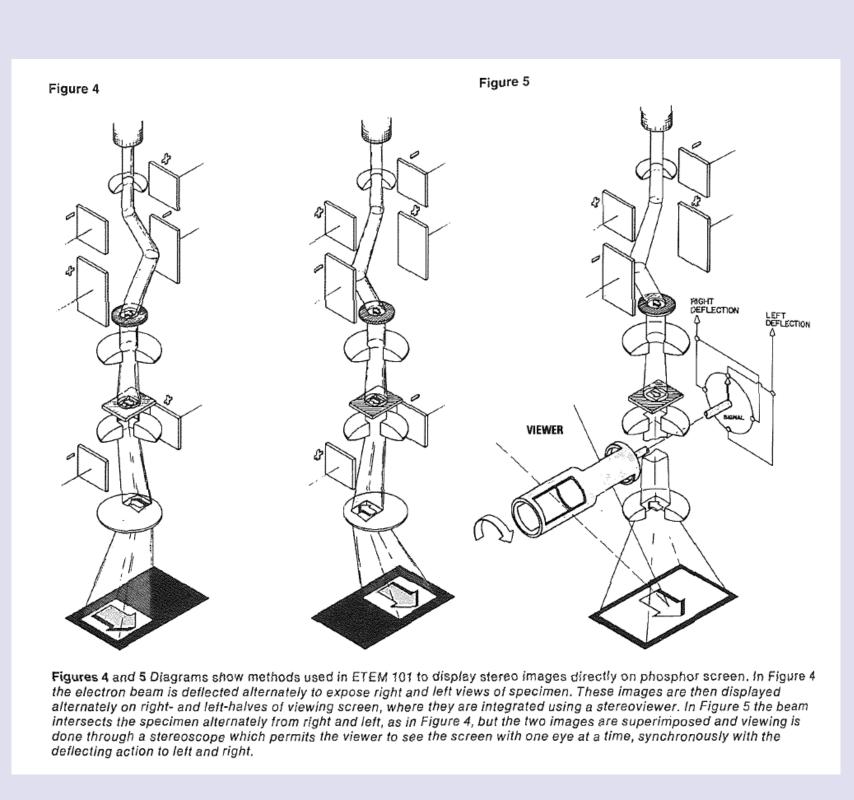
> 10500 s.w. cascade drive tigard, oregon 97223

fort lee, new jersey 07024 (201) 461-3880 western region p.o. box 31153 diamond hts. station san francisco, 94131

## **Method for real-time stereo**

By means of beam tilt, coupled with a shutter-type stereoscope, each eye sees only the image from one tilt direction. This was accomplished by plates below the intermediate lens that shifted the beam, and an aperture above the objective lens that prevented side-by-side overlap. Viewing is in real time, directly on the fluorescent screen. Rempfer patented this system in 1949 while working at Farrand.





## A sample micrograph from an ETEM 101

This image of a thin, stained plastic section of brain tissue shows typical results from an ETEM 101, provided as an "advertising" image. Note that stain granularity of such traditional specimens limits resolution to 2 or 3 nm, so a resolution of 1.2 Å, even at 40 kV, provides perfectly satisfactory results. This was borne out In the 1970s, in a comparison between the ETEM 101 and a Philips EM 300, which was carried out at the Armed Forces Institute of Pathology. An ETEM 101 was still used for routine TEM, with a paper published as late as 1988 (not shown here): Tiekotter, K.L. (1988) Histofluorescent and ultrastructural identification of aminergic processes in the opisthaptor of the marine monogene, Microcotyle sebastis (Polyopisthocotylea: Microcotylinae). Proc. Helminthol. Soc. Wash. 55(2):229-245.

## **Marketing the Elektros ETEM 101**

The ETEM 101 is mounted on hydraulically retractable casters, so it is easily moved. The lenses do not need water cooling, and an air-cooled diffusion pump is used, so it only needs to be plugged into a 120VAC, 10A outlet. It weighs about 700 lbs., so it is stable when the casters are retracted. A special van was used to bring it to exhibits. Although Elektros closed its doors in 1973, results from the ETEM 101 were last displayed at M&M in 2003. An advertising brochure is shown here. About 40 ETEM 101s may have been constructed, but not all were sold. At least 10 survive and three or four are still operational.

• The lens voltages and the accelerating voltage are supplied by the same power supply, so high electrical stability is not necessary. • Electrostatic lenses have no hysteresis or image rotation.

• Electrostatic lenses are self-shielding because there are no magnetic polepieces, which have a magnetic field outside the lens. This also means that the specimen is not in a magnetic field.

• Because there is no leakage of magnetic field between lenses, it is not necessary to align the lenses when changing acceleration voltage or magnification.

• The ETEM 101 uses beam tilt to produce stereo images, which can also be viewed directly on the phosphor screen using a mechanical-shutter viewer synchronized with the beam tilt. The beam-tilt system can also be used as a focus wobbler: By rotating the beam in a circle, an artificially enlarged aperture is created, which makes astigmatism correction (by a six-plate electrostatic stigmator) easier.

• Electronic image shift is available, to which a specimen-drift-correcting voltage ramp can be applied using a joystick. • The stage has 360-degree rotation and 12-degree tilt for (mechanical) stereo. The z-control, used for focusing, has 100-nm dial steps, which

can be used for height measurement. • Focus is independent of magnification, so accurate focus, done at high magnification, does not have to be readjusted at lower magnification.

- The size of the condenser or selected-area aperture can be continuously adjusted by a crossed-forks mechanism.
- The accelerating voltage is continuously adjustable up to 40 kV.
- Resolution is about 12Å.





## Sources

Erik Sanchez, Portland State University, Elektros/Rempfer archives; email exchanges from Ed Sinclair and Dennis Tillman www.vintagetek.org

Rempfer, G., Connell, R., Mercer, L., Louiselle, I. (1972) An electrostatic transmission electron microscope. Am. Laboratory April:39-46. Rempfer, G.F. (1993) Electostatic electron optics in the 1940s and today. MSA Bulletin 23(2):153-158.

Agar, A. (1996) The story of European commercial electron microscopes. In: Mulvey, T. (Ed) Advances in Imaging and Electron Physics. Academic Press. pp 415-584.

Lencova, B. (2008) Electrostatic lenses. In: Orloff, J. (Ed) Handbook of charged particle optics. CRC Press. Orloff, J. (2012) Gertrude Rempfer and the development of high resolution focused ion beam technology. Ultramicroscopy 119:5-8.